



IN THE UNITED STATES

PATENT AND TRADEMARK OFFICE

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TITLE: Inspecting Optical Masks With Electron Beam Microscopy

EXAMINER: Not Yet Known

GROUP ART UNIT: 2878

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OFFICE OF PETITIONS

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner For Patents, Washington, DC 20231, on the date printed below:

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BOX NON-FEE AMENDMENT
COMMISSIONER FOR PATENTS
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PRELIMINARY AMENDMENT

Sir:

Prior to Examination of the above-identified patent application, please amend the specification as follows:

After the section title "CROSS REFERENCE", but before the section title "FIELD OF THE INVENTION", please insert the following paragraph: